PROCEEDINGS OF SPIE

Optical Technology and Measurement for Industrial Applications Conference

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Editors

17–21 April 2023
Yokohama, Japan

Published by
SPIE

Volume 12607

Proceedings of SPIE 0277-786X, V. 12607

Optical Technology and Measurement for Industrial Applications Conference, edited by Takeshi Hatsuzawa, Yukitoshi Otani, Rainer Tutsch, Toru Yoshizawa, Proc. of SPIE Vol. 12607, 1260701 · © 2023 SPIE · 0277-786X · doi: 10.1117/12.3011866

Please use the following format to cite material from these proceedings:
Author(s), "Title of Paper," in *Optical Technology and Measurement for Industrial Applications Conference*, edited by Takeshi Hatsuzawa, Yukitoshi Otani, Rainer Tutsch, Toru Yoshizawa, Proc. of SPIE 12607, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510663411
ISBN: 9781510663428 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time)
SPIE.org

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